

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10509338			
<b>Filing Date:</b>	08-Oct-2004			
<b>Title of Invention:</b>	Method for suppressing charging of component in vacuum processing chamber of plasma processing system and plasma processing system			
First Named Inventor/Applicant Name:	Takehiro Ueda			
<b>Filer:</b>	Marvin Jay Spivak/LaKisha Durham			
<b>Attorney Docket Number:</b>	260055US2SPPCT			
Filed as Large Entity				
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Post-Allowance-and-Post-Issuance:				
<b>Extension-of-Time:</b>				
Extension - 2 months with \$120 paid	1252	1	340	340

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Request for continued examination	1801	1	810	810
Total in USD (\$)				1150